



PATENT

Customer No. 22,852

Attorney Docket No. 07553.0030 (formerly 07363.0010)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Reissue Application of:)

U.S. Patent No.: 5,792,261)

Inventor: Kiichi HAMA et al.)

Issued: August 11, 1998)

Serial No.: 09/478,370)

Filed: February 16, 2000)

For: PLASMA PROCESS
APPARATUS)

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10/23/02
MW

Group Art Unit: 1763

Examiner: L. Alejandro Mulero

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Commissioner for Patents
Washington, DC 20231

Sir:

AMENDMENT

In response to the Office Action dated August 7, 2002, please amend the application as follows:

IN THE CLAIMS:

Please amend the claims as follows:

165. (Amended) An apparatus for processing a process region of a substrate,

using a plasma, comprising:

a container substantially formed of a conductive material;

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